

PCT-150RE TRACK SYSTEM
MASS PRODUCTION WITH 2 TRACKS, DUAL ALLOYS TOOL SET

Please contact Sales sales@picotrack.com for more information



Track System Specification	Description
System designed	US Standard System
System Configuration	TRACK 2: SEND – ALLOY 1 - ALLOY 2 - REC TRACK 1: SEND – ALLOY 1 - ALLOY 2 - REC
System dimension	62" length x 40.50" width x 90" height
Wafer size (workable dual size)	Up to 6" (150mm)
Wafer Sensor	Capacity or Optical
Wafer material	Silicon/Sapphire/GaAs/ Ceramic...
System Controller	PC & PLC Controller with Windows OS based
Robot Arm Transfer Unit	6 Robot Arm
Forearm Arm type	Aluminium clear anodized and silver teflon coated
System enclosure and windows	Yes
ALLOY Module	4 Modules
HPO block type	Aluminum anodized with standoff proximity
Temperature thermal probe	TC
HPO Lid chamber`	Up/down air cylinder control
HPO Temperature controller	Watlow P.I.D with over heating protection
Temperature range	50-400°C, Δt: 50°C ≤ 200s
Temperature uniformity	± 1°C (25-150°C), ± 2°C (151-250°C), ± 3°C (251-400°C)
Wafer Carrier	3 pins controlled by stepper motor
Bake method	Proximity bake, or fixed proximity
Wafer Carrier	3 pins controlled by stepper motor
Wafer Chiller method	N2 Air ring side blow off
Alloy Chamber Exhaust	Top and bottom